Serial No.: 10/826,920 Filed: April 19, 2004

Page : 4 of 12

Amendments to the Claims:

This listing of claims replaces all prior versions and listings of claims in the application:

Listing of Claims:

- 1. (Currently Amended) An apparatus for forming a film having comprising:
- a load chamber;
- a conveyance chamber connected to the load chamber[[,]]; and
- a film formation chamber connected to the conveyance chamber, characterized in that;, wherein the film formation chamber comprises a first evaporation source, means that moves the first evaporation source, a second evaporation source, means that moves the second evaporation source, a third evaporation source, and means that moves the third evaporation source.
- 2. (Currently Amended) The apparatus for forming the film according to claim 1, characterized in that

wherein an installation chamber is connected to the film formation chamber, and wherein the installation chamber is connected to evacuating and exhausting means that evacuates the installation chamber and has a mechanism for setting an evaporation material in the first, second, and third evaporation sources in the installation chamber.

3. (Currently Amended) The apparatus for forming the film according to claim 1, characterized in that

wherein the film formation chamber is connected to an evacuation and exhaust treatment chamber that evacuates the <u>film forming</u> chamber and has means that can introduce <u>for</u> introducing at least one of a material gas or <u>and</u> a cleaning gas.

Serial No.: 10/826,920 Filed: April 19, 2004

Page : 5 of 12

4. (Currently Amended) The apparatus for forming the film according to claim 1, characterized in that

wherein the first, second, and third evaporation sources are movable in an X direction, a Y direction, and a Z direction in the film formation chamber.

5. (Currently Amended) The apparatus for forming the film according to claim 1, characterized in that

wherein the film formation chamber has a shutter that sections the film formation chamber and shields evaporation to the substrate.

6. (Currently Amended) The apparatus for forming the film according to claim 1, characterized in that

wherein a sealing chamber is connected to the conveyance chamber, and
 wherein the sealing chamber is connected to evacuating and exhausting means, which
 evacuates the sealing chamber, and has a mechanism for applying a seal material with an ink jet
 method in the sealing chamber.

- 7. (Currently Amended) An apparatus for forming a film having comprising;
- a load chamber;
- a conveyance chamber connected to the load chamber; and
- a film formation chamber connected to the conveyance chamber, characterized in that;

 wherein the film formation chamber comprises an aligning means that aligns a mask and a substrate, a first evaporation source, means that moves the first evaporation source, a second evaporation source, means that moves the second evaporation source, a third evaporation source, and means that moves the third evaporation source.
- 8. (Currently Amended) The apparatus for forming the film according to claim 7, eharacterized in that

Serial No.: 10/826,920 Filed: April 19, 2004

Page : 6 of 12

wherein an installation chamber is connected to the film formation chamber, and wherein the installation chamber is connected to evacuating and exhausting means that evacuates the installation chamber and has a mechanism for setting an evaporation material in the first, second, and third evaporation sources in the installation chamber.

9. (Currently Amended) The apparatus for forming the film according to claim 7, characterized in that

wherein the film formation chamber is connected to an evacuation and exhaust treatment chamber that evacuates the <u>film forming</u> chamber and has means that can introduce <u>for</u> introducing at least one of a material gas of and a cleaning gas.

10. (Currently Amended) The apparatus for forming the film according to claim 7, characterized in that

wherein the first, second, and third evaporation sources are movable in an X direction, a Y direction, and a Z direction in the film formation chamber.

11. (Currently Amended) The apparatus for forming the film according to claim 7, characterized in that

wherein the film formation chamber has a shutter that sections the film formation chamber and shields evaporation to the substrate.

12. (Currently Amended) The apparatus for forming the film according to claim 7, characterized in that

wherein a sealing chamber is connected to the conveyance chamber, and
 wherein the sealing chamber is connected to evacuating and exhausting means, which
 evacuates the sealing chamber, and has a mechanism for applying a seal material with an ink jet
 method in the sealing chamber.

Serial No.: 10/826,920 Filed: April 19, 2004

Page : 7 of 12

13. (Currently Amended) An apparatus for forming a film having comprising;

a load chamber,

a conveyance chamber connected to the load chamber, and

a film formation chamber connected to the conveyance chamber, characterized in that; wherein the film formation chamber comprises a first evaporation source, means that moves the first evaporation source, a second evaporation source, means that moves the second evaporation source, a third evaporation source, and means that moves the third evaporation source, and

wherein the first, second third evaporation sources have containers with elliptical openings.

14. (Currently Amended) The apparatus for forming the film according to claim 13, eharacterized in that

wherein an installation chamber is connected to the film formation chamber, and wherein the installation chamber is connected to evacuating and exhausting means that evacuates the installation chamber and has a mechanism for setting an evaporation material in the first, second, and third evaporation sources in the installation chamber.

15. (Currently Amended) The apparatus for forming the film according to claim 13, eharacterized in that

wherein the film formation chamber is connected to an evacuation and exhaust treatment chamber that evacuates the film forming chamber and has means that can introduce for introducing at least one of a material gas of and a cleaning gas.

16. (Currently Amended) The apparatus for forming the film according to claim 13, characterized in that

wherein the first, second, and third evaporation sources are movable in an X direction, a Y direction, and a Z direction in the film formation chamber.

Serial No.: 10/826,920 Filed: April 19, 2004

Page : 8 of 12

17. (Currently Amended) The apparatus for forming the film according to claim 13, characterized in that

wherein the film formation chamber has a shutter that sections the film formation chamber and shields evaporation to the substrate.

18. (Currently Amended) The apparatus for forming the film according to claim 13, characterized in that

wherein a sealing chamber is connected to the conveyance chamber, and
 wherein the sealing chamber is connected to evacuating and exhausting means, which
 evacuates the sealing chamber, and has a mechanism for applying a seal material with an ink jet
 method in the sealing chamber.

- 19. (Currently Amended) An apparatus for forming a film having comprising; a load chamber,
- a conveyance chamber connected to the load chamber, and
- a film formation chamber connected to the conveyance chamber, characterized in that; wherein the film formation chamber comprises a first evaporation source, means that moves the first evaporation source, a second evaporation source, means that moves the second evaporation source, a third evaporation source, and means that moves the third evaporation source, and

wherein the first, second third evaporation sources have containers with inclined openings.

20. (Currently Amended) The apparatus for forming the film according to claim 19, characterized in that

wherein an installation chamber is connected to the film formation chamber, and

Serial No.: 10/826,920 Filed: April 19, 2004

Page : 9 of 12

wherein the installation chamber is connected to evacuating and exhausting means that evacuates the installation chamber and has a mechanism for setting an evaporation material in the first, second, and third evaporation sources in the installation chamber.

21. (Currently Amended) The apparatus for forming the film according to claim 19, characterized in that

wherein the film formation chamber is connected to an evacuation and exhaust treatment chamber that evacuates the <u>film forming</u> chamber and has means that can introduce <u>for</u> introducing at least one of a material gas or <u>and</u> a cleaning gas.

22. (Currently Amended) The apparatus for forming the film according to claim 19, characterized in that

wherein the first, second, and third evaporation sources are movable in an X direction, a Y direction, and a Z direction in the film formation chamber.

23. (Currently Amended) The apparatus for forming the film according to claim 19, characterized in that

wherein the film formation chamber has a shutter that sections the film formation chamber and shields evaporation to the substrate.

24. (Currently Amended) The apparatus for forming the film according to claim 19, characterized in that

wherein a sealing chamber is connected to the conveyance chamber, and wherein the sealing chamber is connected to evacuating and exhausting means, which

evacuates the sealing chamber, and has a mechanism for applying a seal material with an ink jet

method in the sealing chamber.

Serial No. : 10/826,920 Filed : April 19, 2004 Page : 10 of 12

25. (Currently Amended) A container for forming a film containing an organic compound by evaporation, characterized in that

wherein the container has an elliptical opening.

- 26. (Currently Amended) The container according to claim 25, characterized in that wherein the container has a prism shape.
- 27. (Currently Amended) A container for forming a film containing an organic compound by evaporation, characterized in that

wherein the container has an inclined opening.

28. (Currently Amended) The container according to claim 27, characterized in that wherein the container has a prism shape.